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| TRANSMITTAL FORM (to be used for all correspondence after initial filing) | Application Number | 10/624,716 |
| | Filing Date | July 21, 2003 |
| | First Named Inventor | Luan C. Tran |
| | Art Unit | 2812 |
| | Examiner Name | Jennifer Kennedy |
| Total Number of Pages in This Submission | Attorney Docket Number | MI22-2357 |

| ENCLOSURES (Check all that apply) | | |
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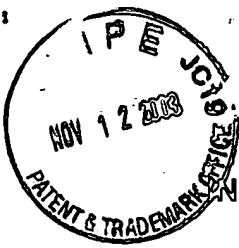
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| Firm or Individual | Jennifer J. Taylor, Ph.D.; Reg. No. 48,711; Wells St. John P.S. |
| Signature | <i>Jennifer J. Taylor</i> |
| Date | <i>November 11, 2003</i> |

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/624,716
Filing Date July 21, 2003
Inventor Luan C. Tran
Assignee Micron Technology, Inc.
Group Art Unit 2812
priority Examiner Kennedy, Jennifer J.
Attorney's Docket No. MI22-2357
Title: Methods of Forming Semiconductor Constructions

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References –See Attached Form PTO-1449

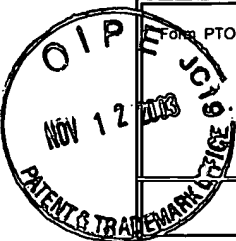
The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included with the exception of U.S. patents and published U.S. applications (Official Gazette Notice: 05 August 2003). No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing date of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. § 1.17(p) to Deposit Account No. 23-0925.

Respectfully submitted,

Dated: November 11, 2003

By: Jennifer J. Taylor
Jennifer J. Taylor, Ph.D.
Reg. No. 48,711



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| Form PTO-1449 | | U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE | | ATTY. DOCKET NO. MI22-2357 | | SERIAL NO. 10/624,716 | |
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| | | | | FILING DATE July 21, 2003 | | GROUP 2812 | |
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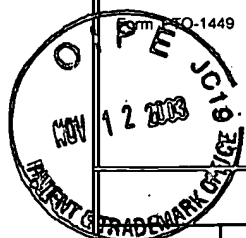
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